

<b>FORM PTO-1449 (MODIFIED)</b>  <b>LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT</b>  (Use several sheets if necessary)	<b>ATTY DOCKET NO.</b>  67,200-377	<b>SERIAL NO.</b>  Filed Herewith
	<b>APPLICANT</b> Fu-Liang Yang	
	<b>FILING DATE</b> Filed Herewith	<b>GROUP</b> Unknown

**REFERENCE DESIGNATION      U.S. PATENT DOCUMENTS**

EXAMINER INITIAL		DOCUMENT NO.	DATE	NAME	CLASS	SUB CLASS	FILING DATE
OP	AA	5,023,671	Jun/1991	DiVincenzo et al			
DF	AB	5,119,151	Jun/1992	Onda			
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						

**FOREIGN PATENT DOCUMENTS**

EXAMINER INITIAL		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION YES/NO
	AK						
	AL						
	AM						
	AN						

**OTHER ART (including Author, Title, Date, pertinent pages, etc.)**

DF	AO	Sallagoity et al, "Analysis of Width Edge Effects in Advanced Isolation Schemes for Deep Submicron CMOS Technologies", IEEE Trans. on Electron Devices, 44(11), Nov. 1996, pp. 1900-05.
DF	AP	Matsuda et al, "Novel Corner Rounding Process for Shallow Trench Isolation Utilizing MSTs (Micro-Structure Transformation of silicon). IEEE IEDM98, pp. 137-40.

EXAMINER

*[Signature]*

DATE CONSIDERED

3/18/04

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to application.